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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/733,217	12/11/2003	Axel Brintzinger	2002 P 12234 US	8003
48154 75	590 10/11/2006		EXAMINER	
SLATER & MATSIL LLP 17950 PRESTON ROAD			· THOMAS, TONIAE M	
SUITE 1000		ART UNIT	PAPER NUMBER	
DALLAS, TX 75252			2822	

DATE MAILED: 10/11/2006

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Application No.	Applicant(s)
Office Antique Com	10/733,217	BRINTZINGER ET AL.
Office Action Summary	Examiner	Art Unit
3	Toniae M. Thomas	2822
The MAILING DATE of this communication app Period for Reply	pears on the cover sheet with the o	correspondence address
A SHORTENED STATUTORY PERIOD FOR REPL' THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a repl If NO period for reply is specified above, the maximum statutory period of Failure to reply within the set or extended period for reply will, by statute Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be tir y within the statutory minimum of thirty (30) day will apply and will expire SIX (6) MONTHS from to cause the application to become ABANDONE	mely filed ys will be considered timely. t the mailing date of this communication.
Status	•	•
1)⊠ Responsive to communication(s) filed on 14 Ju	ulv 2006.	,
	action is non-final.	
3) Since this application is in condition for allowal closed in accordance with the practice under E	nce except for formal matters, pro	
Disposition of Claims		•
4) ☐ Claim(s) 3,4,6,7,9-13 and 16-29 is/are pending 4a) Of the above claim(s) is/are withdraw 5) ☐ Claim(s) is/are allowed. 6) ☐ Claim(s) 3,4,6,7,9-13 and 16-29 is/are rejected 7) ☐ Claim(s) is/are objected to. 8) ☐ Claim(s) are subject to restriction and/or	wn from consideration.	
Application Papers		·
9) The specification is objected to by the Examine	r.	
10) $igtie$ The drawing(s) filed on <u>11 December 2003</u> is/a		
Applicant may not request that any objection to the		
Replacement drawing sheet(s) including the correct 11) The oath or declaration is objected to by the Ex		
Priority under 35 U.S.C. § 119	•	•
a) Acknowledgment is made of a claim for foreign a) All b) Some * c) None of: 1. Certified copies of the priority document 2. Certified copies of the priority document 3. Copies of the certified copies of the priority document application from the International Bureau * See the attached detailed Office action for a list	s have been received. s have been received in Applicati rity documents have been receive u (PCT Rule 17.2(a)).	ion No ed in this National Stage
Attachment(s)		
1) Notice of References Cited (PTO-892)	4) Interview Summary	(PTO-413)
2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date	Paper No(s)/Mail Da	

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DETAILED ACTION

- 1. This Office action is responsive to the amendment filed on 14 July 2006.
- 2. Currently, claims 3, 4, 6, 7, and 9-13, and 16-29 are pending.
- 3. Upon further consideration, the indicated allowability of claims 3, 7, and 15 is withdrawn in view of the previously cited reference to Khandros et al. (US 2004/0201074 A1). A rejection based on the Khandros et al. reference follows.

Claim Objections

4. Claims 23-25 are objected to because of the following informalities: the letter "o" after "surface" and before "the wafer" should be "of" (claim 23, line 3). Appropriate correction is required.

Claim Rejections - 35 USC § 112

The following is a quotation of the second paragraph of 35 U.S.C. 112:

The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.

5. Claim 28 is rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claim 28 as presented in the amendment filed on 14 July 2006 recites the limitation "said step of exposing an underlying surface." Claim 7 does not

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provide antecedent basis for "said step of exposing an underlying surface" as recited in claim 28.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

6. Claims 3, 4, 7, 9-13, and 16-26, 28, and 29 are rejected under 35 U.S.C. 103(a) as being unpatentable over Khandros et al. (US 2004/0201074 A1) in view of Klocke et al. (US 2003/0057093 A1).^{1,2}

The Khandros et al. application publication (referred to hereinafter as Khandros) discloses a method of forming a plurality of three-dimensional structures on a substrate (see fig. 1 and accompanying text). The method comprises the steps of: providing a wafer 116 with bumps, compliant elements 110, distributed on a surface of the wafer (fig. 1; par. 0058, lines 1-4; and par. 0063, lines 1-3); forming a sacrificial layer over the surface including the bumps, and patterning the sacrificial layer to expose and underlying seed layer

¹ The Klocke et al. patent was relied upon in the previous Office action mailed on 20 April 2006.

² Applicant cannot rely upon the foreign priority papers to overcome this rejection because a translation of said papers has not been made of record in accordance with 37 CFR 1.55. See MPEP § 201.15.

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(par. 0073, lines 1-8 and par. 0074, lines 1-3); and forming a plurality of conductors 102 over the exposed seed layer, wherein the conductors electrically connect pads 114 to terminals 104 (fig. 1; par. 0063, lines 3-16; and par. 0074, lines 5-7). Khandros further teaches that the sacrificial layer may be an electrophoretic resist (par. 0073, lines 5-8).

While Khandros teaches that the sacrificial layer can be an electrophoretic resist, Khandros does not explicitly teach forming the electrophoretic resist by: dipping the surface of the wafer into the electrophoretic resist; and applying an electrical voltage between the wafer and the electrophoretic resist.

The Klocke et al. application publication (referred to hereinafter as Klocke) discloses a method of depositing an electrophoretic resist on microelectronic workpieces (par. 9, lines 10-14). The electrophoretic resist is formed by: placing a workpiece into an electrophoretic resist; applying an electrical voltage between the substrate and the electrophoretic resist, while the workpiece is in the electrophoretic resist; and subsequently removing the workpiece from the electrophoretic resist (fig. 17; par. 091, lines 1-19; and par. 0111, lines 1-3). In one embodiment, the method further comprises protecting the rear surface of a workpiece from wetting while the workpiece is placed in the electrophoretic resist (par. 0033, lines 12-18 and par. 48, lines 13-19).

In one embodiment, the method further comprises causing the workpiece to be moved relative to the electrophoretic resist while the workpiece is placed

in the electrophoretic resist (par. 0049, 1-5; par. 0051, 1-5; and par. 0091, lines 9-19). The workpiece is rotated while the workpiece is placed in the electrophoretic resist (par. 0049, lines 1-5; par. 0051, lines 1-5; and par. 0091, lines 9-19). In one embodiment, the electrophoretic resist is stirred while the workpiece is placed in the electrophoretic resist (par. 0049, lines 5-6). The surface of the wafer is dipped into the electrophoretic resist in a horizontal arrangement of the wafer (fig. 2 and par. 0079). The method further comprises heating the workpiece after removing the workpiece from the electrophoretic resist (par. 112, lines 8- 18).

It would have been obvious to one of ordinary skill in the art, at the time the invention was made, to form the electrophoretic resist in Khandros by the method comprising placing a workpiece into an electrophoretic resist, applying an electrical voltage between the substrate and the electrophoretic resist while the workpiece is in the electrophoretic resist, and subsequently removing the workpiece from the electrophoretic resist, as taught by Klocke, because: despite the uneven topography created by the bumps, the coating of resist resulting therefrom conforms uniformly to surface of the wafer.

7. Claims 6 and 27 are rejected under 35 U.S.C. 103(a) as being unpatentable over Khandros in view of Klocke as applied to claims 3 and 13 above, and further in view of Brooks et al. (US 6,084,297).³

³ The Brooks et al. patent was relied upon in the previous Office action mailed on 20 April 2006.

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As explained above, Khandros discloses forming a plurality of conductors 102 over the exposed seed layer. The plurality of conductors may comprise a gold layer formed over a nickel layer (par. 0063, lines 3-10 and par. 0074, lines 5-11).

The Brooks et al. patent (referred to hereinafter as Brooks) discloses forming a plurality of conductors 32 (fig. 1 and col. 5, lines 46-49). The plurality of conductors comprises a copper layer, a nickel layer formed over the copper layer, and a gold layer formed over the nickel layer (col. 5, lines 50-53).

It would have been obvious to one of ordinary skill in the art, at the time the invention was made, to modify the combination of Khandros and Klocke by forming a copper layer over the exposed seed layer prior to forming the nickel layer, as taught by Brooks, since copper has excellent conductivity and can be selectively deposited onto the exposed seed layer using an electroplating method.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Toniae M. Thomas whose telephone number is (571) 272-1846. The examiner can normally be reached on Monday through Friday from 8:30 a.m. to 5:30 p.m.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Zandra Smith can be reached on (571) 272-2429. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-

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9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

TMT30 September 2006

M. Wilczewski Primary Examiner TC 2800

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